

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In Re the Application of:

CHANG-YOUNG JEONG, ET AL.

Application No.:

Filed:

For: **METHOD FOR MANUFACTURING CMOS  
IMAGE SENSOR HAVING MICROLENS  
THEREIN WITH HIGH PHOTSENSITIVITY**

Art Group:

Examiner:

**INFORMATION DISCLOSURE STATEMENT UNDER 37 C.F.R. §1.97**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

In accordance with the duty of disclosure, enclosed is a copy of Information Disclosure Statement by Applicant (form PTO/SB/08), which is being submitted concurrently with the Utility Application. It is respectfully requested that the cited references be considered and that the enclosed copy of PTO/SB/08 be initialed by the Examiner to indicate such consideration and a copy thereof returned to applicant(s).

The submission of this Information Disclosure Statement is not to be construed as a representation that a search has been made in the subject application and is not to be construed as an admission that the information cited in this statement is material to patentability.

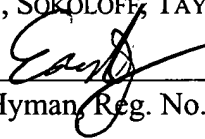
Please charge any fees due to Deposit Account 02-2666. A duplicate copy of the Fee Transmittal (PTO/SB/17) is enclosed for this purpose.

Date: \_\_\_\_\_

12/15/67

Respectfully submitted,

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# **Information Disclosure Statement**

New U.S. Patent Application for  
**METHOD FOR MANUFACTURING CMOS IMAGE SENSOR HAVING  
MICROLENS THEREIN WITH HIGH PHOTSENSITIVITY**

Our Ref. No.: P03H8003/US/gy

## **Reference No.:**

- (1) US Patent No. 6,001,540
- (2) US Publication No. 2002/0102498 A1
- (3) US Publication No. 2002/0114526 A1
- (4) JP Laid-Open No. 4-25073
- (5) JP Laid-Open No. 6-326285
- (6) JP Laid-Open No. 6-326287
- (7) JP Laid-Open No. 8-1809
- (8) JP Laid-Open No. 5-29590
- (9) JP Laid-Open No. 2001-94085
- (10) JP Laid-Open No. 4-129268